

# Tunneling into a quantum confinement created by a single-step nanolithography of conducting oxide interfaces

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A unique nanolithography technique compatible with conducting oxide interfaces, which requires a single lithographic step with no additional amorphous deposition or etching, is presented. It is demonstrated on a SrTiO<sub>3</sub>/LaAlO<sub>3</sub> interface where a constriction is patterned in the electron liquid. We find that an additional backgating can further confine the electron liquid into an isolated island. Conductance and differential conductance measurements show resonant tunneling through the island. The data at various temperatures and magnetic fields are analyzed and the effective island size is found to be of the order of 10 nm. The magnetic field dependence suggests the absence of spin degeneracy in the island. Our method is suitable for creating superconducting and oxide-interface-based electronic devices.

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## I. INTRODUCTION

When free electrons are confined into a structure whose dimensions are smaller than their Fermi wavelength, their energy states become quantized. The resulting electronic level spacing increases as the dimensions of the confinement region decrease. The gate voltage can tune the chemical potential to match between the discrete spectrum of the confinement and the continuum in the reservoir realized by the leads. Such matching or resonance occurs when the electronic population in the confinement region is changed by a single electron. In addition to the level spacing, adding a single electron to the confinement requires surmounting the charging energy  $E_C = \frac{e^2}{2C}$ , with  $C$  the capacitance. This energy is usually larger than the spacing between the levels in the confinement, for most metallic and semiconducting dots. Such single electron transistors (SETs) have been realized in many semiconductor devices [1].

While in semiconductor devices unconfined electrons can be described in the noninteracting particles picture, two-dimensional electron gas formed at the interface between the insulating oxides SrTiO<sub>3</sub> and LaAlO<sub>3</sub> [2] can undergo a variety of phase transitions [3–6], and electronic correlations should be taken into account [7,8]. It has been shown that backgating can be very efficient for carrier modulation in mesoscopic samples on SrTiO<sub>3</sub> as a result of field focusing by the large dielectric constant [9]. However, nanolithography in SrTiO<sub>3</sub>-based interfaces is challenging due to its sensitivity to vacancies and impurities, resulting in spurious parallel conductivity [10].

In order to define a conducting channel for a SrTiO<sub>3</sub>/LaAlO<sub>3</sub> interface, usually an amorphous hard mask [11] is used. This process requires more than one deposition step [12]. Another option to define nanostructures is using a conducting atomic force microscope (AFM) tip biased against the SrTiO<sub>3</sub>/LaAlO<sub>3</sub> interface below its conductivity threshold of four unit cells [13]. This method has proven to be very useful for producing nanometric devices, in particular, a SET

[14]. However, neither the backgate nor topgate can be used, and the resulting devices are sensitive to temperature cycles and electric fields.

Here, we demonstrate a simple lithography technique applicable to conducting oxide heterostructures, which requires only a single step of lithography and deposition. The hard mask can be defined with a resolution of sub-10 nm [15]. Applying this method, we successfully fabricated narrow quantum constrictions resulting in a quantum-dot (QD) formation inside the constriction and performed the electron level spectroscopy of the dot.

## II. METHODS

In order to define a nanometric constriction we used a unique lithography approach. We spin coated atomically flat TiO<sub>2</sub>-terminated SrTiO<sub>3</sub> substrates with 140 nm of hydrogen silsesquioxane (HSQ). The devices were then defined using  $e$ -beam lithography. This results in a hard mask of amorphous SiO<sub>2</sub> ( $a$ -SiO<sub>2</sub>) on top of the SrTiO<sub>3</sub>. Then, 10 unit cells of epitaxial LaAlO<sub>3</sub> were deposited using pulsed laser deposition, as described in Ref. [16]. Gold gate electrodes were evaporated to cover the back of the substrate. The leakage current was unmeasurably small (<1 pA) in the entire range of applied voltages. In some samples, the gate voltage range under study varied from one cooldown to another. Conductance and differential conductance were measured using a lock-in amplifier-based technique.

## III. RESULTS AND DISCUSSION

### A. Characterization of the devices

In Fig. 1(a) we show a scanning electron microscope (SEM) image of one of the defined structures (sample B2). Electrical conductance appears only in the SrTiO<sub>3</sub> regions under the crystalline LaAlO<sub>3</sub> ( $c$ -LaAlO<sub>3</sub>) while the regions under the  $a$ -SiO<sub>2</sub> are insulating. An overall view of the device is shown in Fig. 1(b); the electrical circuit connection configuration is noted. Ti/Au pads are deposited after ion milling through the LaAlO<sub>3</sub> layer to form ohmic contacts with the conducting interface between the  $c$ -LaAlO<sub>3</sub> and SrTiO<sub>3</sub> [Fig. 1(b)]. In

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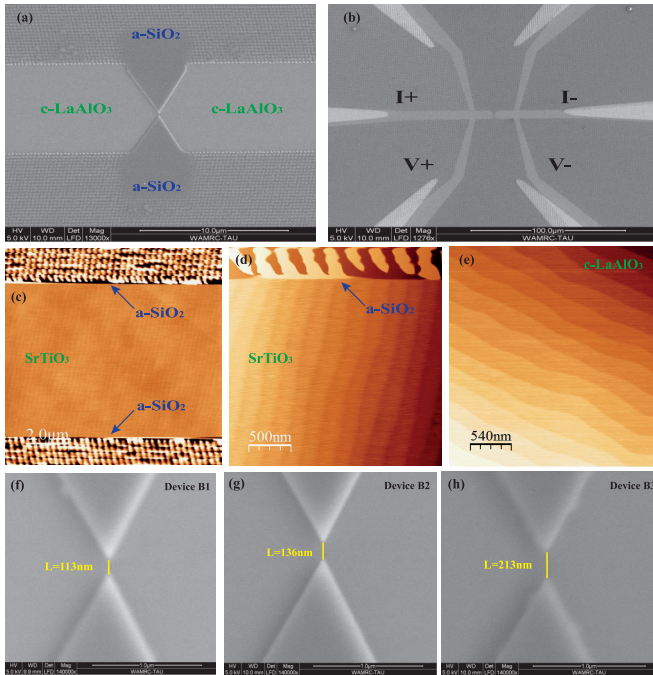


FIG. 1. (a) SEM image of the HSQ electron-beam-lithography pattern of sample B2. The two different regions (conducting crystalline and amorphous insulating) are marked ( $c\text{-LaAlO}_3$  and  $a\text{-SiO}_2$ ). (b) Overview SEM image showing the device structure and contact configuration for sample B2. (c), (d) AFM images of a patterned HSQ hard mask, which corresponds to the  $c\text{-LaAlO}_3$  region in (a) (image taken before  $\text{LaAlO}_3$  deposition). The sharp contrast between the  $a\text{-SiO}_2$  and the atomically smooth  $\text{SrTiO}_3$  is conspicuous. No traces of the  $a\text{-SiO}_2$  are visible in the  $\text{SrTiO}_3$  regions. (e) AFM image of one of the  $c\text{-LaAlO}_3$  contacts (before ion milling). A clear step-terrace structure is observed that is compatible with the  $\text{LaAlO}_3$  unit cell. (f)–(h) SEM images focused on the constriction regions of samples B1, B2, and B3; their sizes are marked by yellow lines.

Fig. 1(c) we show an AFM image of a hard HSQ mask on  $\text{SrTiO}_3$ . The HSQ was removed from regions unexposed to the electron beam. Figure 1(d) focuses on the vicinity of the  $\text{SrTiO}_3$ -HSQ boundary. From both Figs. 1(c) and 1(d) it is clear that the HSQ is completely removed from the desired regions, leaving an atomically flat  $\text{SrTiO}_3$  surface with the typical step-terrace morphology. In Fig. 1(e) we show an AFM image of the  $c\text{-LaAlO}_3$  region. The step-terrace morphology is indicative of an atomically flat and crystalline  $\text{LaAlO}_3$  layer. In Figs. 1(f)–1(h) we show constrictions with increasing sizes, demonstrating our capability to control the device dimensions.

In Fig. 2 we show the resistance versus gate voltage data taken at 1.6 K for samples B1–B3 whose corresponding images are shown in Figs. 1(f)–1(h). As expected, the resistance is increasing with negative gate voltage, but an unusual pattern of dips and peaks appears at a certain onset voltage. This onset increases monotonically with the size of the constriction, as shown in the inset of Fig. 2. For sample A, similar gate scans are shown in the Supplemental Material (Fig. S1 [17]). In sample A, for a constriction size of 370 nm, we could not see the dip-peak structure with gate voltages of up to  $-60$  V. The geometry of these five devices defers from each other only by the constriction size (samples A and B were made

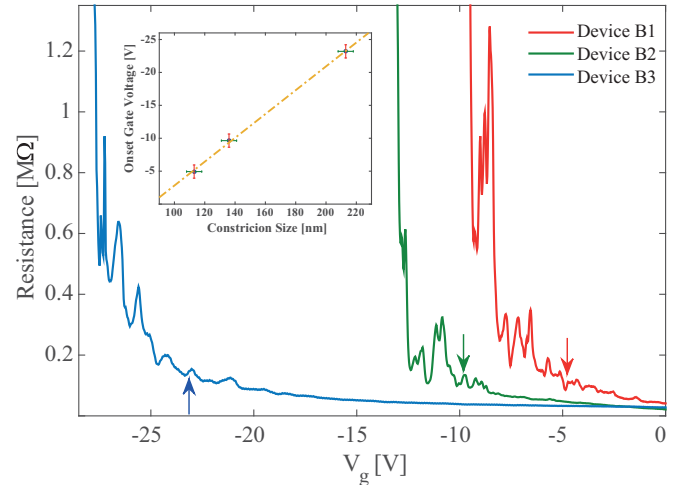


FIG. 2. Resistance vs gate voltage sweeps measured at 1.6 K for samples B1–B3, whose images are presented in Figs. 1(f)–1(h). Arrows depict the gate voltage where the dip-peak structure onsets. The inset shows the extracted onset gate voltage vs the nominal constriction size. The line is a guide to the eye.

on different substrates). Namely, they have the same bridge width and feature angles. We further note that samples of similar size that lack the sharp-edge-constriction geometry exhibit resistance, which is monotonic with backgate voltage, suggesting that the effect we observe is not related to intrinsic inhomogeneities due to disorder over a length scale of a few 10 nm (see Fig. S2 [17]).

In conclusion, we conjecture that the dip-peak pattern is a result of tunneling through an isolated conducting island formed in the constriction. The necessary conditions for the island formation are sharp features and a narrow constriction.

## B. Quantum-dot characteristics and analysis

It is possible to accumulate electrons in the island using either a backgate ( $V_g$ ) or drain-source voltage ( $V_{ds}$ ). Scanning both gate voltages should result in diamond-shaped regions of low conductance in the  $V_g$ - $V_{ds}$  diagram. Such a plot is shown in Fig. 3(a) for sample A1 at 1.5 K and in Fig. 3(b) for sample B2 at 160 mK.

The reservoir is coupled capacitively to the island through two main channels whose capacitances are  $C_l$  and  $C_{bg}$  for the leads and the backgate, respectively. The slope of the diamonds is therefore  $\alpha \simeq \frac{C_{bg}}{C_l + C_{bg}}$ . From both diamond plots [Figs. 3(a) and 3(b)] we estimate  $\alpha$  to range between 0.004 and 0.006. The variations of  $\alpha$  with backgate voltages can be attributed to the changing dielectric constant of the  $\text{SrTiO}_3$  [18] and the resulting change in the self-capacitance of the island.

The extremely large value of the dielectric constant ( $\sim 24000$ ) [19] makes the  $\text{SrTiO}_3$  material very unique in the context of tunneling through the confined region, since the charging energy (Coulomb blockade) is expected to be suppressed by over three orders of magnitude relative to devices of similar sizes made of metals and most semiconductors.  $E_C$  is therefore negligible compared to the level spacing for such confined regions with dimensions of up to  $1 \mu\text{m}$ . Consequently

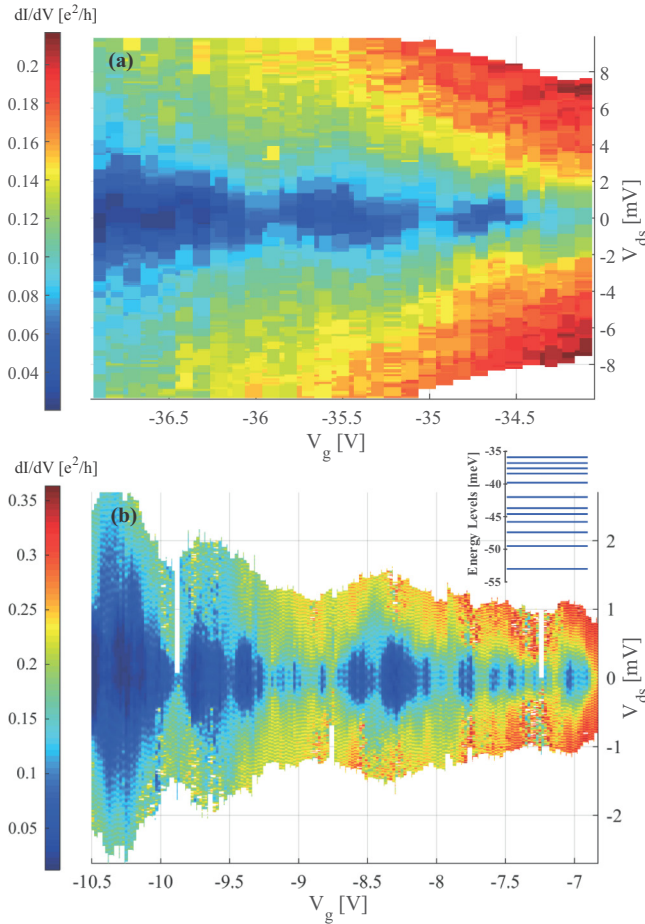


FIG. 3. (a) and (b) Color coded differential conductance ( $dI/dV_{ds}$ ) of samples A1 and B2 at 1.5 K and 160 mK, respectively, as a function of both the bias voltage  $V_{ds}$  and the backgate voltage  $V_g$ . Resistive diamond regions (blue) are seen in both samples. Note that the color code for (b) is rescaled for clarity compared to (a). We plot the matching energy levels of sample B2 in the inset of (b) using the calculated conversion factor  $\alpha$ . The variations in the level spacing are the usual ones typically observed for a generic quantum dot in the presence of impurities and/or an irregular boundary.

the Coulomb blockade can be ignored, as mentioned. Indeed,  $C = 8\epsilon_0\epsilon_r R$  is the self-capacitance of a disk of radius  $R$ , and estimating the level spacing to be  $\Delta\epsilon = \frac{\hbar^2}{m^* R^2}$  for free electrons in a two-dimensional confinement, where  $m^* = 0.7m_e$  is the effective mass of the lower band of SrTiO<sub>3</sub>/LaAlO<sub>3</sub> [20] (for the low carrier concentration studied we expect only the lowest band to be populated), we obtain that  $E_C = \delta\epsilon$  when  $R = 30 \mu\text{m}$ . Therefore,  $E_C \ll \Delta\epsilon$  for all possible island sizes within our constriction limited to a few hundred nanometers. This implies that our measurement is a direct probe of the density of states of the island  $\nu(\epsilon)$ . Similar arguments were given by Cheng *et al.* [14].

In an ideal QD the diamond-shaped regions with vanishing conductance should be separated by sharp conductance peaks. In our case the entire picture is shifted by a conducting background and the features are asymmetric and somewhat broadened. It is possible that the islands in the various samples

cannot be pictured as an isolated single QD. Rather, it is likely that another nonresonant channel exists.

### C. Fano-type behavior and temperature dependence

Whenever resonant and nonresonant scattering paths interfere, an asymmetric Fano line shape should appear. Fano resonances have been observed in a wide range of experiments including GaAs/AlGaAs QDs [21,22]. Taking the Fano scattering formula and treating it within the Landauer-Büttiker formalism, Göres *et al.* obtained an expression which describes the most general case of coexistence of resonant and nonresonant channels:

$$G = G_{\text{inc}} + G_0 \frac{(\xi + q)^2}{\xi^2 + 1}, \quad (1)$$

where  $\xi = [\epsilon - \epsilon(0)]/(\Gamma/2)$  is the dimensionless parameter becoming larger when the energy  $\epsilon$  is shifted away from the resonant one,  $\epsilon(0)$ .  $\Gamma$  is the width of the resonant feature,  $q$  is the asymmetry parameter, and  $G_{\text{inc}}$  denotes an incoherent contribution to the conductance.

In Fig. 4(a) we show the conductance through the island of sample B1 measured at 220 mK. Different asymmetric dips and peaks can be observed. Fitting each dip/peak to the Fano formula [Eq. (1)] gives various asymmetry parameters  $q$ , which correspond to the phase shift of the resonant signal with respect to the nonresonant one.

In Fig. 4(b) we show the conductance through the island of sample A1 at various temperatures. The width of the peaks and the dips is reduced with lowering the temperature. In addition, more features appear below  $\simeq 1$  K.

By fitting the data of sample A1 at various temperatures [Fig. 4(b)] and sample B2 (see Fig. S3 [17]) to Eq. (1) in the special case of a symmetric Breit-Wigner peak, which corresponds to the Fano formula in the limit  $q \rightarrow \infty$  and  $G_0 \rightarrow 0$ , we can extract the width at half maxima of the resonance features [full width at half maximum (FWHM)]. In Fig. 4(b) we show examples for three such fits at  $V_g = -43.2$  V. In Fig. 4(c) we show the extracted FWHM for samples A1 and B2.

If the temperature is not too low ( $k_B T > \Gamma/20$ ) one expects the FWHM of an electronic Lorentzian-type feature to be broadened as  $\simeq 3.5k_B T$  due to the temperature dependence of the Fermi-Dirac distribution. The measured FWHM in units of the gate voltage is related to the electronic energy by the conversion factor  $\alpha$ . The linear fits and the resulting  $\alpha$ 's are presented in Fig. 4(c). The average  $\alpha = 0.0044 \pm 0.0005$  is in reasonable agreement with the estimated value obtained from Fig. 3.

### D. Level spacing calculation and discussion of dot size

Now we can calculate the level spacing ( $\Delta\epsilon$ ) using the voltage difference between conductance peaks and the conversion factor  $\alpha$ .  $\Delta\epsilon$  varies with gate voltage, possibly due to decreasing dielectric constant. We estimate  $\Delta\epsilon$  to be between 1 and 5 meV, yielding an estimated island size of 5–10 nm. This size estimation further supports our statement that the charging energy is negligible compared to the level spacing. The island size is different than the geometrical size of the constriction.

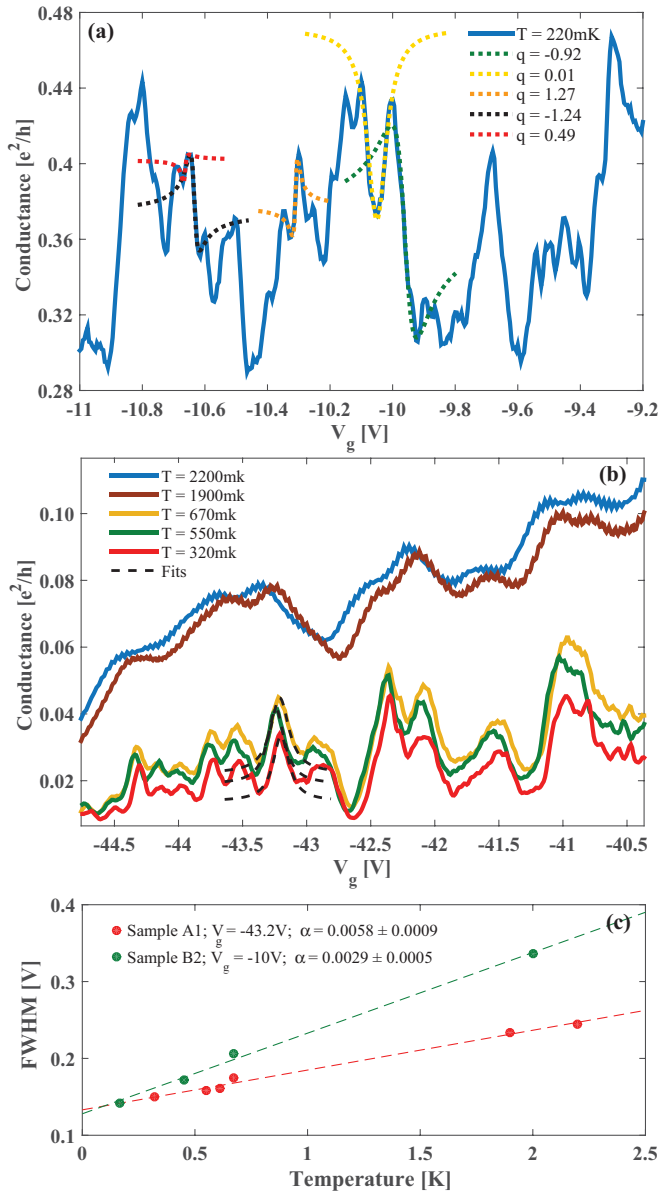


FIG. 4. (a) Conductance vs  $V_g$  for sample B1 at 220 mK. Five different fits to Eq. (1) are shown. The asymmetry parameter  $q$  is noted for each fit. (b) Conductance vs  $V_g$  for sample A1 measured at various temperatures. Three fits to Eq. (1) in the special case of a symmetric Breit-Wigner peak are presented for a particular  $V_g = -43.2$  V. (c) FWHM extracted from the fits in (b) and similar ones, as a function of temperature for two different gate voltages for sample A1 (b) and sample B2 (see also Fig. S3 [17]). The dashed lines are linear fits. The resulting  $\alpha$  factor (see text) is shown for each fit.

What is the reason for the order of magnitude difference between the obtained dot size (10 nm) and the lithographic dimension of the constriction (100 nm)? We have previously shown that the efficiency of the backgate improves significantly when the typical size of the sample becomes smaller than the screening length [8,9]. For the typical size of our constriction, the geometry of sharp edges, and the large nonlinear dielectric constant, we expect stray fields to become important. We conjecture that this causes an additional

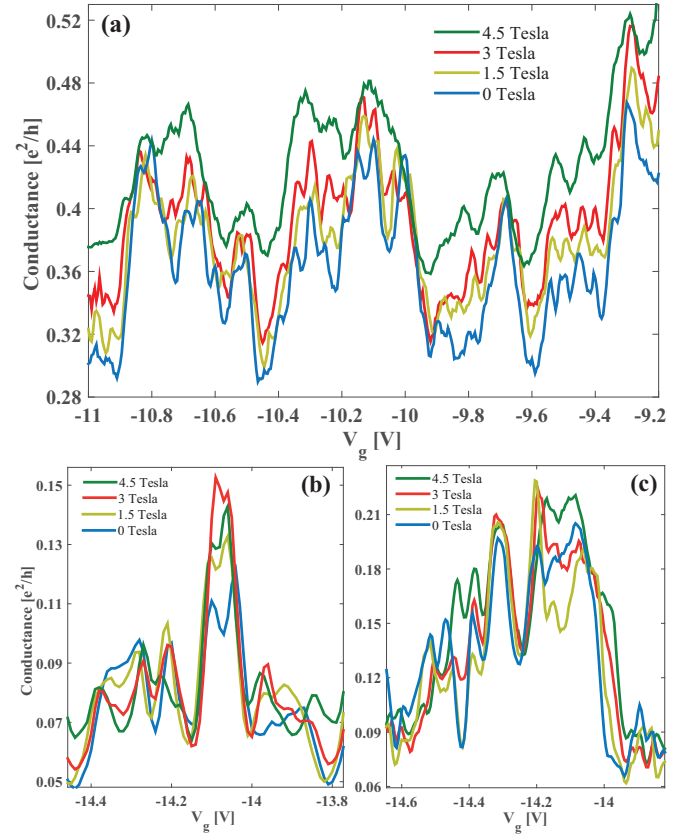


FIG. 5. (a) Conductance vs  $V_g$  for various magnetic fields applied perpendicular to the interface for sample B1 at 220 mK. (b) and (c) Conductance vs  $V_g$  for sample B2 for various magnetic fields applied perpendicular to the interface at 220 mK (b) and perpendicular to the current (transverse) at 160 mK (c).

electrostatic confinement resulting in a small conducting island surrounded by a depleted region inside the constriction. Furthermore, the monotonic dependence of the onset gate voltage versus constriction size (Fig. 2) and the absence of island formation for a constriction size of 370 nm (Fig. S1 [17]) support this scenario in which a larger (negative) gate voltage is needed to deplete the surroundings of the quantum dot formed.

Another view is that the QD is formed due to the modified sample properties in a shallow region near the HSQ barrier. However, we demonstrate in Fig. 1 that the SrTiO<sub>3</sub>/LaAlO<sub>3</sub> remains intact in the vicinity of the HSQ, and we demonstrate in Figs. 2 and S1 [17] a monotonic dependence of the onset gate voltage on a constriction size up to 370 nm where the effect vanishes. Both these findings provide support for the electrostatic scenario we propose above.

### E. Magnetic field dependence

In Fig. 5 we show the magnetic field dependence in two field orientations. The main important observation is the absence of level splitting up to magnetic fields of 6 T (see also Figs. S4 and S5 [17]). This suggests that the levels are not spin degenerate at the low carrier regime. For free electrons one

expects a Zeeman splitting equivalent to a gate bias of 0.1 V, well within the resolution of our measurements. An absence of spin degeneracy is also observed in ballistic transport in quantum wires [23].

Our results are different than Cheng *et al.* [14], where spin splitting by a magnetic field is observed. It is possible that this is related to the difference between the LaAlO<sub>3</sub> layer below (Cheng *et al.*) and above (this paper) the critical thickness [24]. We also note that magnetic effects have been related to the titanium  $d_{xy}$  band, which is presumably the first to be populated in our quantum dot [25].

Overall, looking at the magnetic field dependence, in the perpendicular configuration the conductance background increases and the features are weakened [see Figs. 5(a) and S5 [17]]. Sometimes a nonmonotonic behavior is observed, as shown in Figs. 5(b) and 5(c) for perpendicular and transverse field orientations, respectively. We attribute these observations to the magnetic flux threading between the interfering resonant and nonresonant paths [21]. Indeed, the above phenomena occur on a magnetic field scale corresponding to a flux quantum per square of size 20–30 nm (the magnetic length), which is larger than the calculated island size (10 nm), yet within the constriction (200 nm for sample A1 and 140 nm for sample B2). More work is still needed to clarify all the details of the magnetic field dependence in the different orientations.

A strong spin-orbit interaction could have resulted in an opposite effect, namely, enhancement of coherent backscattering with an applied magnetic field (similar to antilocalization). However, at the low carrier concentration regime in which the resonant and nonresonant channels interfere in our samples, the spin-orbit interaction is strongly suppressed [26]. We also note that, in this low carrier regime, superconductivity is fully suppressed [8].

#### IV. CONCLUSION

In summary, we developed a single-step lithography process suitable for conducting oxide interfaces. This process does not require any additional etching, lift-off, or deposition of an amorphous layer. Using this process we were able to create a nanometric conducting island from a SrTiO<sub>3</sub>/LaAlO<sub>3</sub> interface. Conductance through this island exhibits features characteristic of a quantum dot—these features do not split at magnetic fields as high as 6 T, but they are suppressed by an additional parallel nonresonant current path. We analyzed our results within the framework of a resonant channel interfering with a nonresonant one. From this analysis we find that the size of the island is of the order of 10 nm. This size is much smaller than the lithographic size of the constriction. We conjecture that the geometry of sharp edges and the large nonlinear dielectric constant causes an additional electrostatic confinement. This lithography and electrostatic definition of the conducting regions can be used in future superconducting and electronic devices.

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